

### Amendments to the Abstract

*Kindly amend the original abstract with the following rewritten abstract:*

#### ABSTRACT

A substrate holding apparatus can meet the request for a smaller-sized compact apparatus while ensuring a sufficient immersion depth of a substrate in a processing liquid. The substrate holding apparatus includes: a substrate holder (84)-for supporting a substrate (W) by bringing a peripheral portion of a surface of the substrate (W) into contact with a first sealing member (92); and a substrate pressing section (85)-for lowering relative to the substrate holder (84) so as to press the substrate (W) held by the substrate holder (84) downward, thereby bringing the a first sealing member (92) into pressure contact with the substrate (W); wherein the. The substrate pressing section (85)-is provided with a second ring-shaped sealing member (170)-which makes pressure contact with an upper surface of a ring-shaped holding section of the substrate holder (84), thereby sealing the peripheral region of the substrate pressing section (85).